

Notice of References Cited	Application/Control No. 09/819,552	Applicant(s)/Patent Under Reexamination GABRIEL ET AL.	
	Examiner Binh X Tran	Art Unit 1765	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,500,605	12-2002	Mullee et al.	430/329
	B	US-6,319,655	11-2001	Wong et al.	430/311
	C	US-6,207,583	03-2001	Dunne et al.	438/725
	D	US-6,054,254	04-2000	Sato et al.	430/322
	E	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Deep-UV Lithography", http://courses.nus.edu.sg/course/phyweets/Projects98/OPTICAL/deep.html
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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